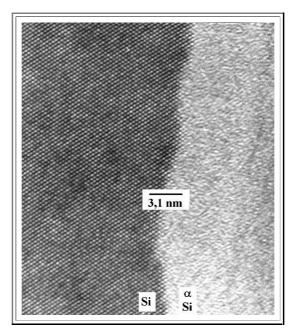
Amorphization after Ion Implantation

- The picture below shows the boundary between crystalline **Si**, and **Si** that has been rendered *amorphous* by an ion implantation (the ion beam came from the right). The picture is slightly remarkable because it was the first <a href="https://doi.org/10.1007/jhi/high-ncs/linearing-
 - There is indeed an amorphous **Si** (α-**Si**) layer. (Think a minute how you could ascertain that without transmission electron microscopy).
 - There is a pretty abrupt, if somewhat wavy boundary between the amorphous and the crystalline Si.
 - There seems to be little disturbance in the Si lattice it looks pretty perfect.



- Quick glances at HRTEM pictures may be deceiving, however.
 - A lot of point defects may be contained in the lattice they would not clearly show in this picture
 - Looking a bit more closely at some greater depth (to the left of the above picture), a high density of dislocations is found. An example is shown below; the ending lattice planes are indicated with yellow lines.
 - Note that not all dislocations will show up in this kind of imaging mode.

